

	Type	L #	Hits	Search Text	DBs	Time Stamp
1	BRS	L1	3	kim near seong-wook.in.	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT; IBM_T DB	2004/12/0 8 11:09
2	BRS	L2	677	438/199.ccls.	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT; IBM_T DB	2004/12/0 8 11:10
3	BRS	L3	8	2 and (ddd)	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT; IBM_T DB	2004/12/0 8 11:17

	Type	L #	Hits	Search Text	DBs	Time Stamp
4	BRS	L4	6	2 and (double-diffused)	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT; IBM_T DB	2004/12/0 8 11:21
5	BRS	L5	13	2 and (double-diffused or ddd)	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT; IBM_T DB	2004/12/0 8 11:25
6	BRS	L6	11924	(double-diffused or ddd)	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT; IBM_T DB	2004/12/0 8 11:26

	Type	L #	Hits	Search Text	DBs	Time Stamp
7	BRS	L7	85	(double-diffused or ddd) near15 ((spacer\$1 or sidewall\$1) or (side near wall\$1))	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT; IBM_T DB	2004/12/0 8 11:48

	U	1	Document ID	Title	Current OR
1			US 20020123182 A1	TRANSISTOR WITH ULTA-SHORT GATE FEATURE AND METHOD OF FABRICATING THE SAME	438/199
2			US 20020102780 A1	Semiconductor device and manufacturing method thereof	438/199
3			US 20020048914 A1	METHOD OF FABRICATING A SEMICONDUCTOR DEVICE OF HIGH-VOLTAGE CMOS STRUCTRE	438/549
4			US 6806134 B2	Sidewall strap for complementary semiconductor structures and method of making same	438/233

	U	1	Document ID	Title	Current OR
5			US 6746906 B2	Transistor with ultra-short gate feature and method of fabricating the same	438/199
6			US 6512273 B1	Method and structure for improving hot carrier immunity for devices with very shallow junctions	257/369
7			US 6391698 B1	Forming complementary metal-oxide semiconductor with gradient doped source/drain	438/199
8			US 6255152 B1	Method of fabricating CMOS using Si-B layer to form source/drain extension junction	438/199

	U	1	Document ID	Title	Current OR
9			US 6187620 B1	Integrated circuit having sacrificial spacers for producing graded NMOS source/drain junctions possibly dissimilar from PMOS source/drain junctions	438/230
10			US 6069031 A	Process to form CMOS devices with higher ESD and hot carrier immunity	438/197
11			US 5837572 A	CMOS integrated circuit formed by using removable spacers to produce asymmetrical NMOS junctions before asymmetrical PMOS junctions for optimizing thermal diffusivity of dopants implanted therein	438/199

	U	1	Document ID	Title	Current OR
12			US 5702988 A	Blending integrated circuit technology	438/238
13			US 4318750 A	Method for radiation hardening semiconductor devices and integrated circuits to latch-up effects	438/798